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PATENT APPLICATION  
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kenji NISHI

Application No.: 10/026,909

Filed: December 27, 2001



Group Art Unit: 2851

Examiner: H. Nguyen

Docket No.: 111586

For: MANUFACTURING METHOD IN MANUFACTURING LINE, MANUFACTURING METHOD FOR EXPOSURE APPARATUS, AND EXPOSURE APPARATUS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. English-language Abstracts of the non-English language reference is attached hereto.
- ☒ 3. A computer-generated English translation of the following Japanese Patent Publication has been obtained from the website of the Japanese Patent Office (<http://www.jpo.go.jp>), and is attached, but has not been reviewed for accuracy.

Respectfully submitted,

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